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In_{0.69}Al_{0.31}As_{0.41}Sb_{0.59}/In_{0.27}Ga_{0.73}Sb double-heterojunction bipolar transistors with InAs_{0.66}Sb_{0.34} contact layers

J.G. Champlain, R. Magno, R. Bass, D. Park and J.B. Boos

Presented are the first DC and RF results for a double heterojunction bipolar transistor, at a 6.2 Å lattice constant, incorporating InAs_{0.66}Sb_{0.34}. These devices show excellent performance with a high collector current density of 1.9×10^5 A/cm², high breakdown voltage over 2.5 V, high short-circuit current gain cutoff frequency of 59 GHz, and maximum frequency of oscillation of 34 GHz.

Introduction: The 6.1 Å materials, and by extension the 6.2 Å materials, have shown great promise for low-power, high-speed performance owing to a large range of available bandgaps, band offsets, and high electron and hole mobilities [1–4]. Diodes fabricated in the 6.2 Å material system have shown high current densities at very low voltages, leading to devices that consume half the power of similar InP-based devices and a fifth the power of similar GaAs-based devices. In this Letter, the first In_{0.69}Al_{0.31}As_{0.41}Sb_{0.59}/In_{0.27}Ga_{0.73}Sb double-heterojunction bipolar transistors (HBTs) incorporating InAs_{0.66}Sb_{0.34} for use as the emitter contact and sub-collector layers is presented. Use of InAs_{0.66}Sb_{0.34} results in a significant improvement in performance over the first reported HBTs in this material system [5]. These devices show excellent DC and RF performance with the highest measured short-circuit current gain cutoff frequency (f_T) for an HBT fabricated in this material system.

Growth and fabrication: The HBTs were grown by solid-source molecular beam epitaxy (MBE) using As₂ and Sb₂ from valved cracking sources. From substrate to surface, the growth consisted of a semi-insulating (SI) GaAs substrate; a buffer of 3000 Å GaAs, 12 Å AlSb, 5000 Å Al_{0.65}Ga_{0.35}Sb, and 1 μm of In_{0.21}Ga_{0.19}Al_{0.60}Sb; a 5000 Å n⁺ (Te: 4×10^{18} cm⁻³) InAs_{0.66}Sb_{0.34} sub-collector; a 1950 Å n In_{0.69}Al_{0.31}As_{0.41}Sb_{0.59} collector consisting of a 400 Å doping grade (Te: $4 \times 10^{18} \sim 5 \times 10^{16}$ cm⁻³) adjacent to the subcollector, a 1500 Å low doped (Te: 5×10^{16} cm⁻³) region, and a 50 Å UID layer adjacent to the base; a 1000 Å p⁺ (Be: 3×10^{19} cm⁻³) In_{0.27}Ga_{0.73}Sb base; a n In_{0.69}Al_{0.31}As_{0.41}Sb_{0.59} emitter consisting of a 500 Å moderately doped (Te: 2×10^{17} cm⁻³) layer adjacent to the base, a 90 Å doping grade (Te: $2 \times 10^{17} \sim 6.7 \times 10^{18}$ cm⁻³), and a 210 Å highly doped (Te: 6.7×10^{18} cm⁻³) layer adjacent to the emitter contact layer; and a 100 Å n⁺ (Te: 9.6×10^{18} cm⁻³) InAs_{0.66}Sb_{0.34} emitter contact. InAs_{0.66}Sb_{0.34} has been shown to have superb electron transport properties and offers extremely low contact resistance when used for n-type ohmic contacts, making it an excellent choice for the n-type emitter contact and sub-collector layers [6]. Alternatively, In_{0.27}Ga_{0.73}Sb has been shown to have excellent hole transport properties and results in extremely low resistance, p-type contacts, making it an ideal choice for the p-type base layer [7].

The HBTs were fabricated using standard processing and e-beam lithography techniques. The emitter and collector n-type contacts consisted of an unannealed Ti:Pt:Au (100:50:2500 Å) stack [6]. The base p-type contact consisted of an unannealed Pd:Pt:Au (100:50:2500 Å) stack [7]. The emitter mesa was defined using a tartaric-based wet etch, with the base mesa defined by SiCl₄-based ICP RIE. The tartaric-based etch used for the emitter mesa etch is non-selective, requiring a thicker base layer ($t_{base} = 1000$ Å) to guarantee a good yield. After device isolation by a wet etch, co-planar ground-signal-ground waveguides were deposited onto the SI GaAs substrate with airbridges to the relevant HBT contacts.

Measurements, results, analysis: The Gummel plot and common-emitter collector characteristics for an HBT with a $2 \times 10 \mu\text{m}^2$ emitter contact area are shown in Figs. 1 and 2, respectively. The area of the base-emitter junction, measured by scanning electron microscopy (SEM), is approximately $1.4 \times 9.4 \mu\text{m}^2$, owing to undercutting during the emitter wet etch. The device shows excellent base and collector idealities of $\eta_B = 1.5$ and $\eta_C = 1.0$, respectively. The improvement of the base ideality (η_B) and high base-emitter voltage before the diodes become resistively limited, as compared to previous results [4, 5, 8], suggest that the inclusion of InAs_{0.66}Sb_{0.34} for the emitter contact and sub-collector layers has reduced the relative series resistance seen by

each junction, improving the overall performance of the device. The low current gain, $\beta = I_C/I_B = 2 - 3$, is believed to be due to Be diffusion into the emitter, removing the efficacy of the base-emitter heterojunction, as similar device structures have yielded current gains as high as $17 \sim 20$ [4, 5, 8]. As can be seen from the collector characteristic in Fig. 2, the HBT exhibits a high collector current density of $I_C = 1.9 \times 10^5$ A/cm². The high collector current at low base-emitter biases demonstrates the excellent low voltage operation of these devices. Relatively large breakdown voltages ($V_{CE,bkdn} > 2.5$ V) at low currents have been measured.

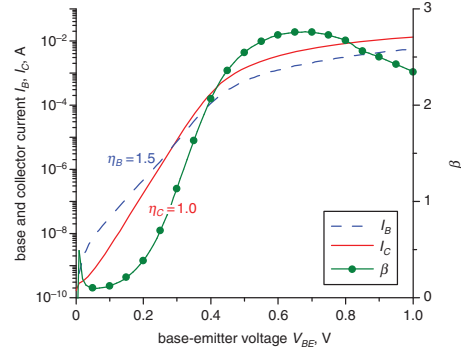


Fig. 1 Gummel plot of $2 \times 10 \mu\text{m}^2$ HBT showing base current (I_B), collector current (I_C), and current gain (β)

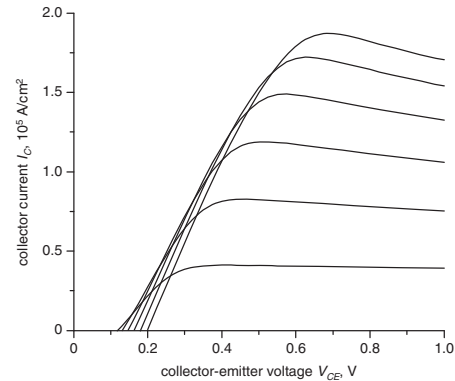


Fig. 2 Common-emitter collector characteristics of $2 \times 10 \mu\text{m}^2$ HBT. Base current (I_B) stepped from 0 to 12 mA with 2 mA steps

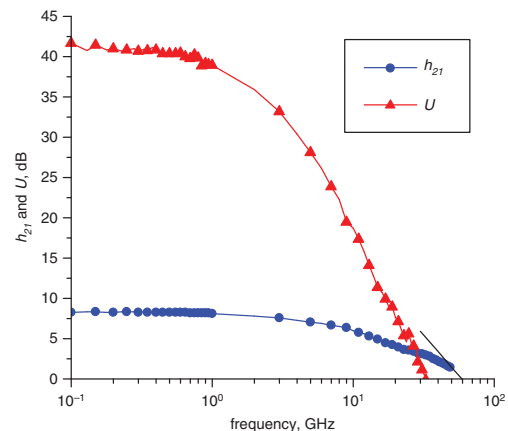


Fig. 3 Plot of short-circuit current gain (h_{21}) and Mason's unilateral gain (U) at $V_{CE} = 1$ V and $I_C = 7.6 \times 10^4$ A/cm²

The measured short-circuit current gain (h_{21}) and Mason's unilateral gain (U) for $V_{CE} = 1$ V and $I_C = 7.6 \times 10^4$ A/cm² are shown in Fig. 3. The maximum measured short-circuit current gain cutoff frequency was $f_T = 59$ GHz with an associated maximum frequency of oscillation of $f_{max} = 34$ GHz ($V_{CE} = 1$ V, $I_C = 7.6 \times 10^4$ A/cm²; Fig. 4). f_{max} in

these devices is limited by the device geometry (base-emitter contact spacing of $\sim 1 \mu\text{m}$, base contact width of $2 \mu\text{m}$, collector thickness of 1550 \AA) resulting in an estimated base resistance of $R_B = 12.3 \Omega$, base-collector capacitance of $C_{BC} = 148.5 \text{ fF}$, and an associated f_{max}/f_τ ratio of 0.61 (with $f_\tau = 59 \text{ GHz}$), very close to the measured ratio of $f_{\text{max}}/f_\tau = 0.57$. f_{max} is expected to improve by nearly a factor of 2.5 simply through proper device scaling. Additionally, a selective etch for the emitter mesa definition would facilitate the use of a thinner base [8], which should improve f_τ .

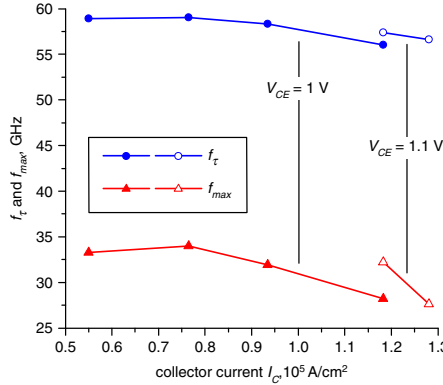


Fig. 4 Plot of short-circuit current gain cutoff frequency (f_τ) and maximum frequency of oscillation (f_{max}) against collector current (I_C) and collector-emitter voltage (V_{CE})

Conclusions: $\text{In}_{0.59}\text{Al}_{0.31}\text{As}_{0.41}\text{Sb}_{0.59}/\text{In}_{0.27}\text{Ga}_{0.73}\text{Sb}$ double-heterojunction bipolar transistors incorporating $\text{InAs}_{0.66}\text{Sb}_{0.34}$ in the emitter contact and sub-collector layers have been demonstrated. These HBTs show excellent DC performance and RF performance with a high collector current density ($I_C = 1.9 \times 10^5 \text{ A/cm}^2$), relatively large breakdown voltage ($V_{CE, \text{bkdn}} > 2.5 \text{ V}$), a maximum $f_\tau = 59 \text{ GHz}$ (the highest measured for this material system), and $f_{\text{max}} = 34 \text{ GHz}$.

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One or more of the Figures in this Letter are available in colour online.

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